

Enabling Nanoscale Advances



Park PinPoint™ mode

PinPoint your sample with AFM

Accurate nanomechanical and electrical imaging
using PinPoint™ mode

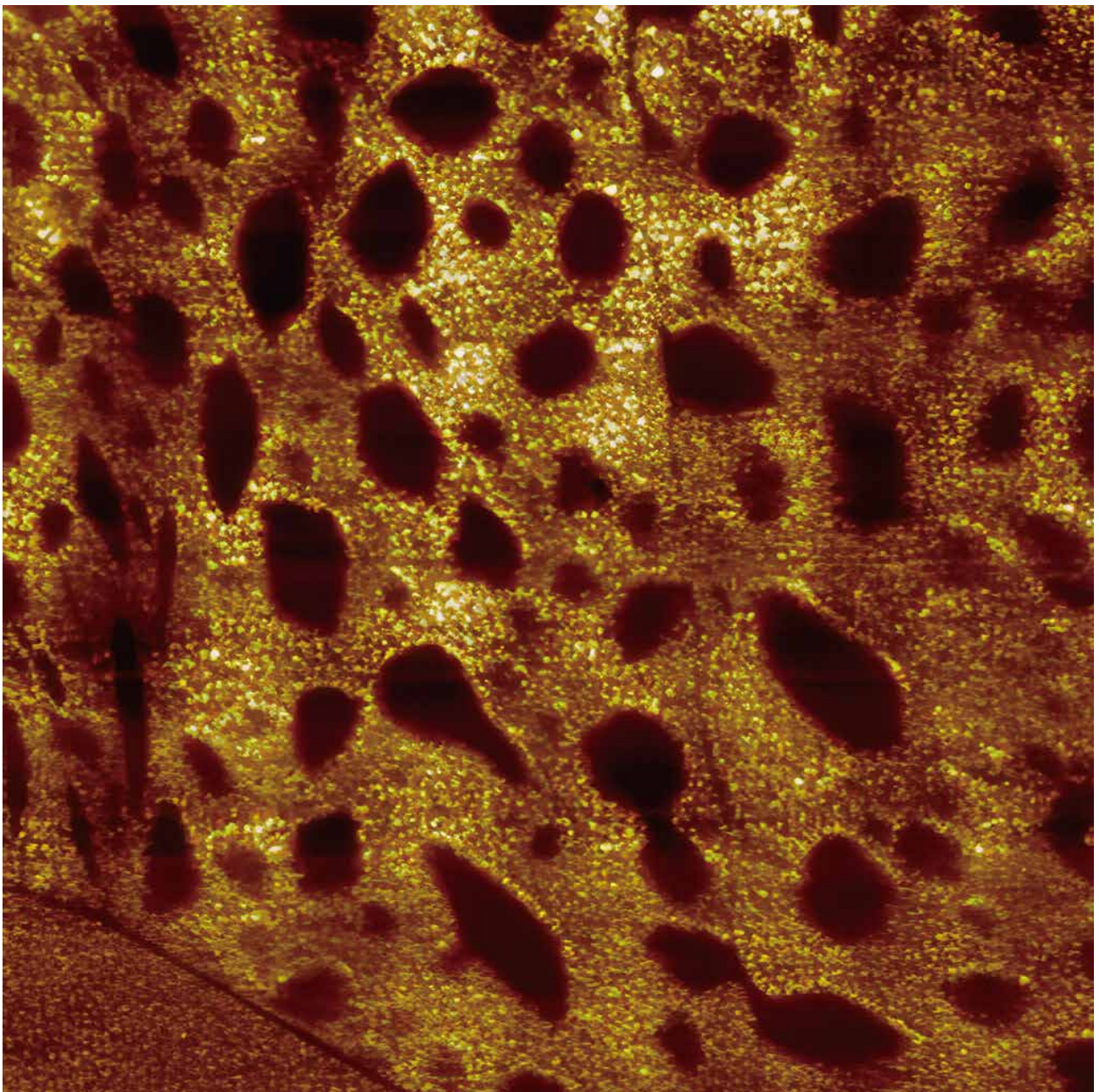


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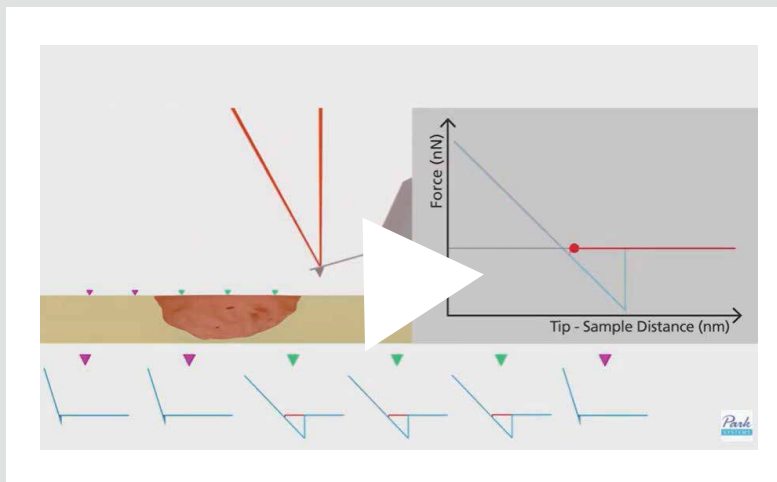
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PinPoint modes for electrical and electromechanical characterization:

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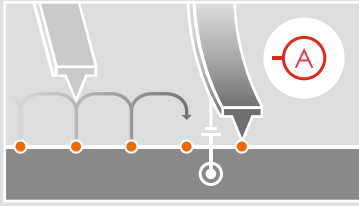
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Scan QR code to watch an instructive video on Park PinPoint™ mode.

What is PinPoint™ mode



PinPoint is a proprietary operation mode of Park Systems AFMs that provides accurate and quantitative nanomechanical imaging via fast force spectroscopy mapping. Precise control of the contact force and movement speed of the cantilever allows the acquisition of nanomechanical properties such as adhesion force and elastic modulus. Moreover, an adjustable contact time enables the

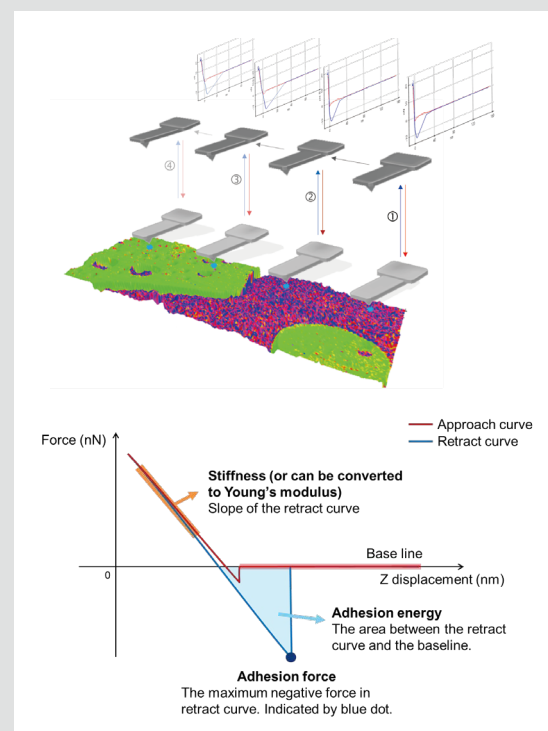
combination of PinPoint with several other electrical AFM modes like conductive AFM (C-AFM), Piezoresponse Force Microscopy (PFM), and Scanning Spreading Resistance Microscopy (SSRM). PinPoint therefore enables more accurate and less invasive characterization by integrating advanced AFM modes for the simultaneous measurement of mechanical and electrical properties.

How does PinPoint work?

In PinPoint mode, the XY scanner stops at each pixel, and the cantilever approaches and retracts to record high-speed force-distance curves with precise control of contact force and contact time between the tip and the sample. For example, an image with 256 x 256 pixels equates to 65,536 measurements, simultaneously acquiring 3D topography and nanomechanical information at each contact point.

PinPoint mode has the capability to simultaneously collect topography, stiffness, elastic modulus, and adhesion force in real-time. Since the cantilever is lifted between each force-distance curve, PinPoint ensures a frictionless operation that eliminates shear forces while enabling sub-nm contact forces, and therefore preserves tip and sample conditions.

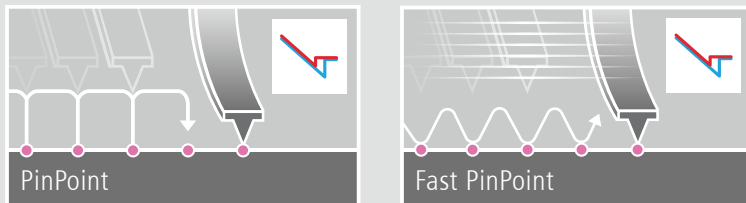
- PinPoint can be combined with various electrical and electromechanical measurement modes.
- PinPoint allows a non-invasive characterization of soft samples, that are sensitive to shear forces.
- It offers simultaneous acquisition of up to eight unique information channels.
- Users can fully customize acquisition channels to meet different experimental requirements.
- Precise control of the contact time at the setpoint (maximum loading force) optimizes tip-sample interaction.
- The stationary XY scanner during each force-distance cycle ensures highly accurate and reproducible measurements.



Working principle of PinPoint nanomechanical mode by Park Systems. the probe moves sequentially from point 1 to 4, and at each point force-distance curves are taken to calculate the nanomechanical properties.

Fast PinPoint™ mode

Fast PinPoint is an advanced mode that measures nanomechanical properties, such as modulus and adhesion, while simultaneously capturing high-resolution topography at high speed. It is ideal for structures that change over time as it allows for fast data acquisition.



Working principles

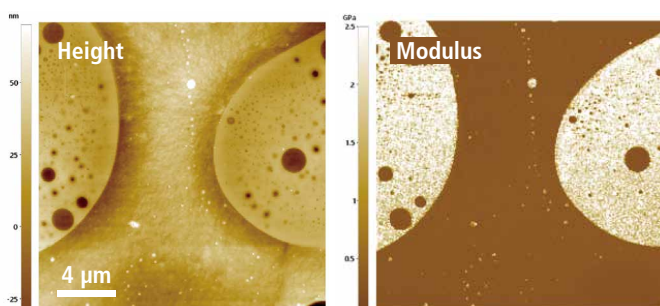
- Acquires sinusoidal F/d curves at each contact point during the imaging
- Precise force control with minimized lateral forces for accurate results
- Non-destructive measurement suitable for sensitive samples

Advantages:

Fast PinPoint operates at low modulation frequencies from 100 Hz to 2 kHz and recording images 8 times faster than the standard PinPoint mode (~2 min for 128 × 128 pixels). Such high scan speed is crucial for mechanical characterization of soft materials like polymers, composites, and biological samples.

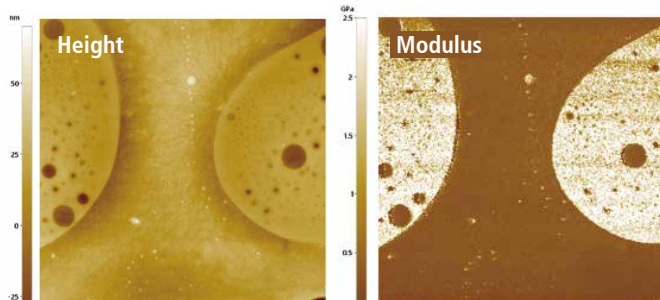
■ PS/LDPE

PinPoint



Scan Rate: 0.13 Hz
Imaging Time: ~33 min

Fast PinPoint



Scan Rate: 1 Hz
Imaging Time: ~4.3 min

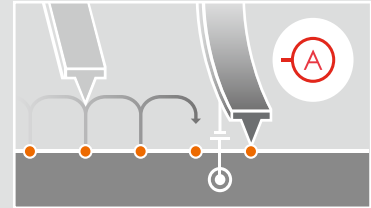
Reference Modulus

PS: ~2.25 GPa
LDPE: ~0.316 GPa

PinPoint C-AFM

PinPoint C-AFM for highly reproducible, non-invasive current imaging

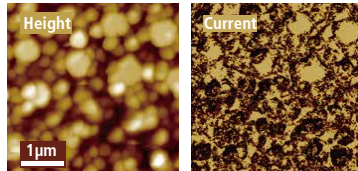
PinPoint C-AFM provides higher accuracy in both topography and current measurements compared to traditional C-AFM through:



- Reduced shear forces, preserving tip quality and extending tip lifetime
- Higher spatial resolution as a result of lower tip wear
- Controlled contact force and contact time for highly accurate current detection
- Preservation of sample integrity, particularly on soft, polymeric surfaces
- Simultaneous acquisition of conductive, topographical and nanomechanical information

■ ZnO Nanorods

PinPoint C-AFM



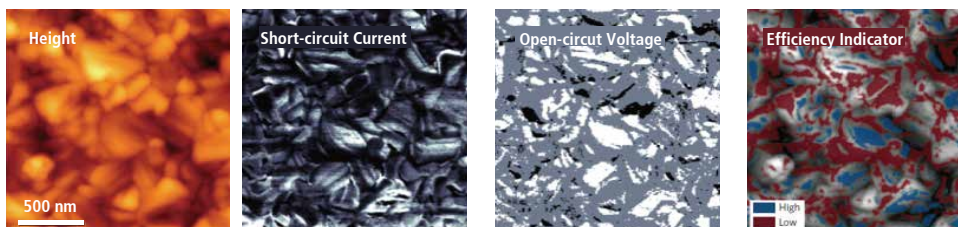
Topography and current images acquired using PinPoint C-AFM and conventional C-AFM.

Conventional C-AFM



PinPoint C-AFM provides stable and reproducible current imaging, while conventional C-AFM shows scan-direction-dependent contrast.

■ Hybrid Halide Perovskite Solar Cell



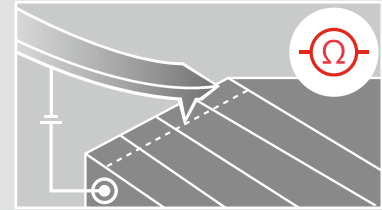
Spatial variations in short-circuit current (I_{sc}) and open-circuit voltage (V_{oc}) are observed within individual perovskite grains, distinguishing high- and low-efficiency regions.

Sibel Y. Leblebici et al. (2016). Facet-dependent photovoltaic efficiency variations in single grains of hybrid halide perovskite. Nature Energy 16093.

PinPoint SSRM

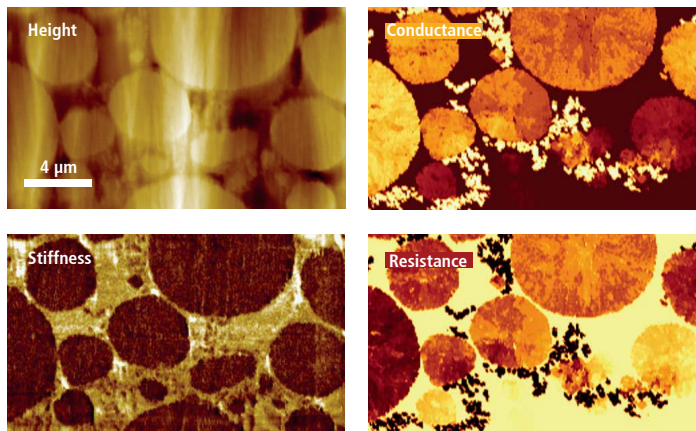
PinPoint SSRM for semiconductor and energy materials applications

PinPoint SSRM provides higher accuracy in electrical measurements compared to conventional SSRM through:



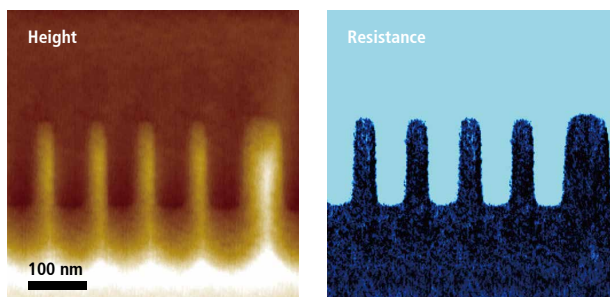
- Reduced shear forces for longer tip lifetime and less sample damage
- More accurate detection of electrical signals due to controlled contact force and contact time
- Simultaneous acquisition of current, conductance, resistance, topography, and nanomechanical properties

■ Li-ion Battery Electrode



Topography, conductance, resistance, and stiffness were simultaneously measured on Park NX-Hivac under vacuum condition.

■ Ge ALE on Patterned Wafer



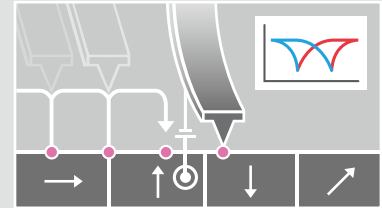
SSRM resistance imaging clearly resolves patterned Ge structures after ALE processing.

Electrical contrast reveals etch-dependent variations across the sidewalls and recessed regions.

PinPoint PFM

PinPoint PFM for enhanced piezoresponse characterization at the nanoscale

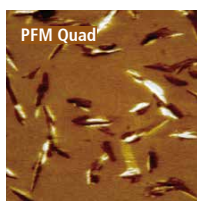
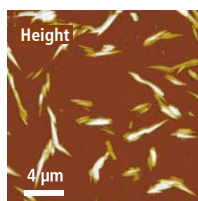
PinPoint PFM provides non-invasive piezoresponse measurements with improved accuracy compared to conventional PFM through:



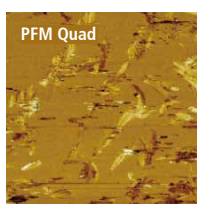
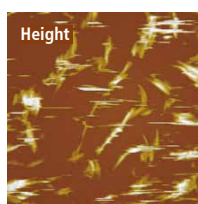
- Controlled contact force and contact time for repeatable and accurate piezoresponse measurements
- High spatial resolution due to reduced tip wear
- Non-invasive imaging particularly suitable for soft samples and samples weakly adhered to the substrate, enabled by reduced shear forces.
- Simultaneous acquisition of piezoresponse, topography and nanomechanical properties

■ Annealed Phenanthrene

PinPoint PFM



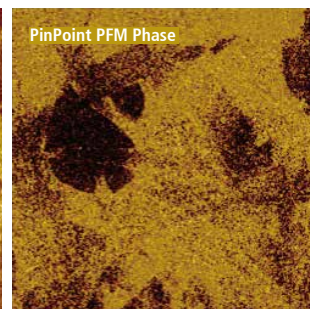
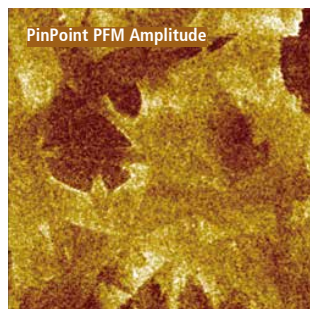
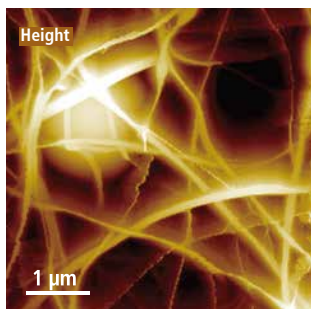
Conventional PFM



Height and PFM quad images of annealed phenanthrene reveal the piezoresponse distribution of the crystalline domains.

PinPoint PFM provides clearer and more stable contrast compared to conventional PFM due to reduced lateral forces.

■ PVDF Fibrous Membrane

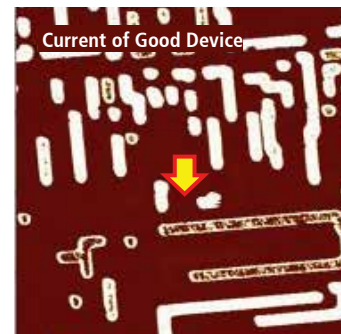
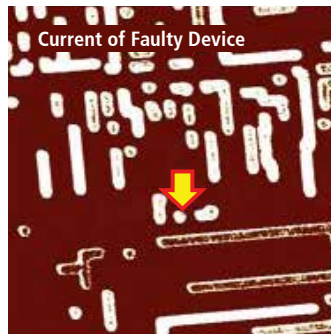
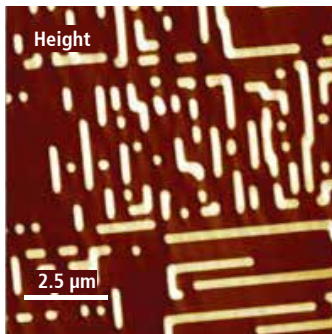


Height, PFM amplitude, and phase images reveal ferroelectric domain structures in the PVDF fibrous membrane.

Sample courtesy: M. Sucea, IMT Bucharest, Romania P Pascariu, Petru Poni Institute, Romania

Application Examples - Electrical Characterization

▪ Failure Analysis of Semiconductor Devices using PinPoint C-AFM

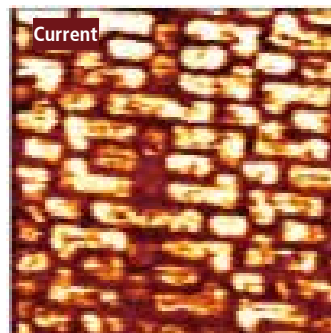
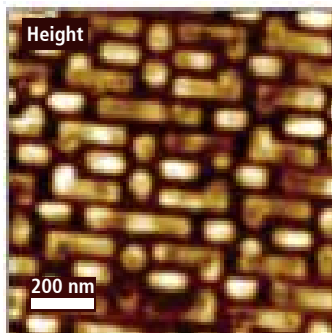


Localized current mapping enables failure analysis of semiconductor devices.

* The defect is clearly marked by the yellow arrow.

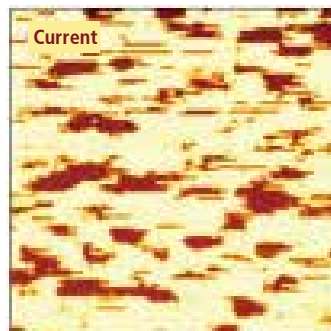
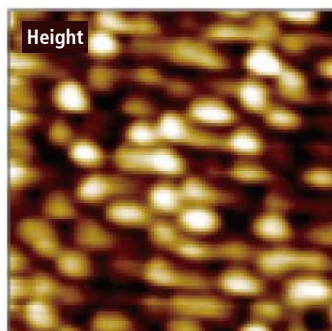
▪ Metallic Conduit Wiring Layer in a 6T SRAM (22 nm Node)

PinPoint C-AFM



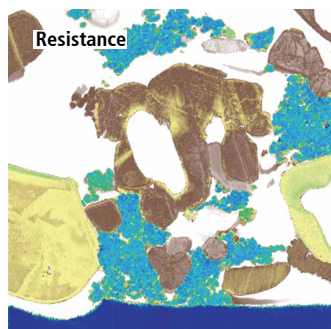
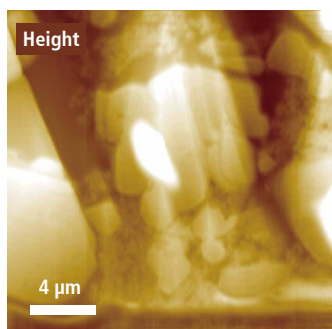
PinPoint C-AFM enables stable and high-resolution current imaging of nanoscale interconnect structures.

Conventional C-AFM



Compared with conventional C-AFM, improved electrical contrast allows clearer identification of conductive paths.

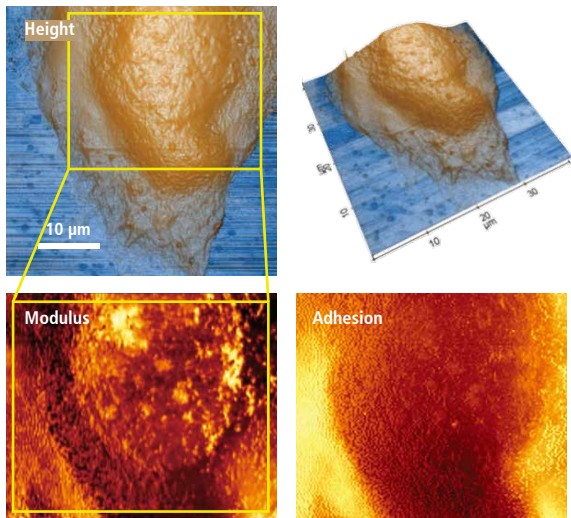
▪ Li-ion Battery on Si Substrate using PinPoint SSRM



SSRM imaging reveals variations in local electrical resistance across the Li-ion battery electrode on a silicon substrate.

Application Examples - Nanomechanical Characterization

▪ MRC-5 Cell (Human Lung Fibroblast)

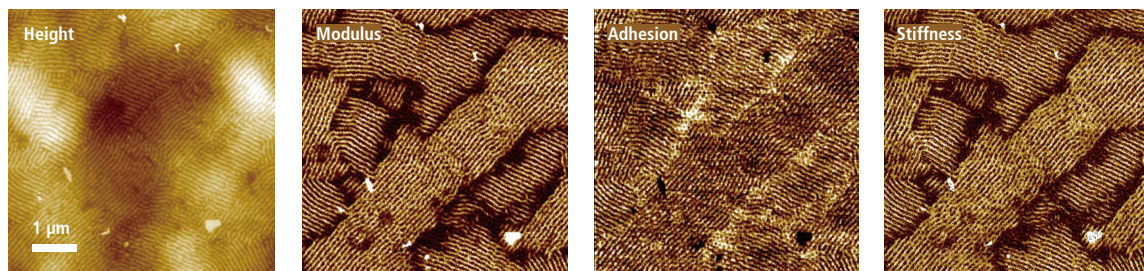


Nanomechanical imaging reveals local variations in stiffness and adhesion across the MRC-5 cell surface.

The stiffness and adhesion force ranges measured in PinPoint mode are approximately 90 kPa and 400 pN, respectively.

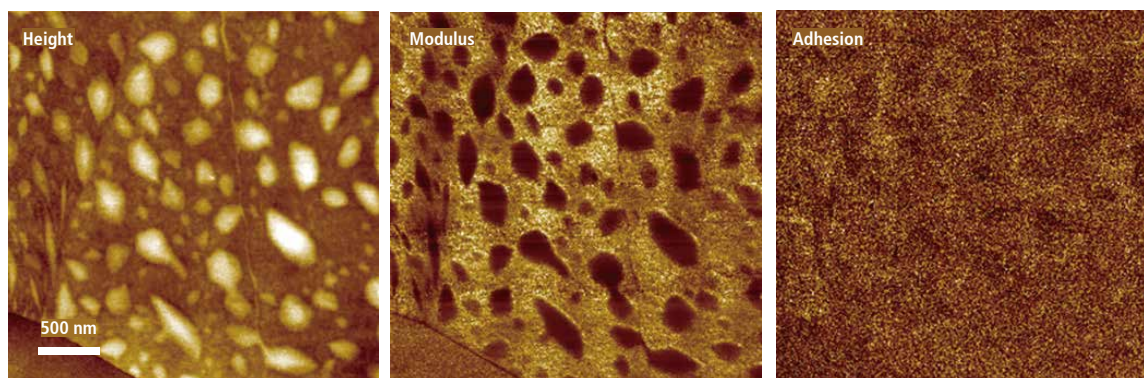
Simultaneous acquisition of topography and force-distance data minimizes positional errors and reduces sample damage, enabling reliable nanomechanical characterization of soft biological samples.

▪ PS-PMMA Block Copolymer



Nanomechanical contrast in modulus, adhesion, and stiffness clearly distinguishes polymer domains.

▪ MoS₂ Bubbles

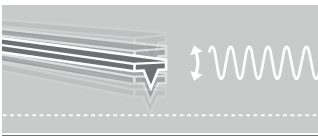
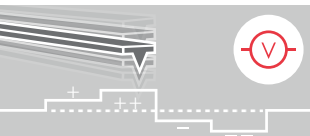
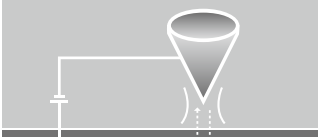
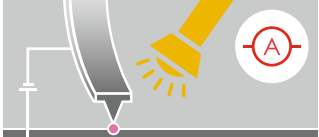
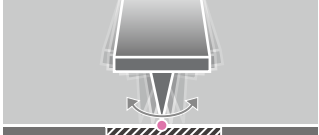
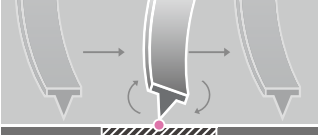
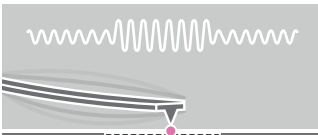
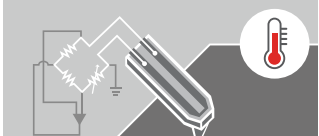
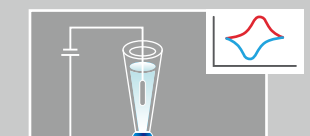


Modulus contrast clearly identifies bubble-like features and local mechanical variations in MoS₂.

Sample courtesy: Institut für Festkörperphysik, Universität Bremen, Germany

Park Atomic Force Microscopy Modes

Get the data you need with Park's selection of scanning modes

TOPOGRAPHY MODE			ELECTRICAL MODE
			
True Non-Contact™ Mode	Contact Mode	Tapping Mode	KPFM
			
C-AFM	PinPoint™ Nanoelectrical	sMIM	PFM
			
EFM	Current-Voltage Spectroscopy	SCM	SSRM
NANOMECHANICAL MODE			
			
STM	PCM	Fast PinPoint™ Nanomechanical	Force-Distance Spectroscopy
			
PinPoint™ Nanomechanical	TFM	LFM	Nanoindentation
SPECIAL MODE			
			
FMM	PiFM	SmartLitho™	MFM
			
SICM	SthM	EC-AFM	SECCM

The Leading Innovator of Nanometrology Solutions

Park Systems is a leading manufacturer of AFMs and other nanoscale metrology instruments for both research and industrial applications.

AFM

Atomic Force Microscope
Ultimate Nano-Scale Metrology



Industrial Metrology

Manufacturing Process Control



WLI

White Light Interferometer
3D Optical Metrology



DHM

Digital Holographic Microscope
Real-Time 3D Optical Metrology



ISE

Imaging Spectroscopic Ellipsometer
Wide Field-of-View
Thin-Film Characterization



AVI

Active Vibration Isolation
Environmental Vibration Noise Isolation



Enabling Nanoscale Advances

150, Gwacheon-daero 12-gil, Gwacheon-si, Gyeonggi-do, Republic of Korea
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